Experimental setup



- Date: 09.01.2015 to 12.01.2015
- Crystal: AOXB19-11-70

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- Laser power loss in KTN (reflection, absorption): 2.4% +/- 0.7% (N = 7)
- Laser power loss in wedge attenuator: 7.7% +/- 0.5% (N = 7)
- Laser power incident on KTN crystal = 111% Measured laser power

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Beam profile and TEC PWM duty cycle references

Setup for $2w_f = 0.50 mm$



Camera in position of first KTN surface



1 mm

Camera in measurement position: 280 mm behind first KTN surface (2w = 0.96 mm) ۲

Camera in position of first KTN surface

Setup for $2w_f = 0.22 mm$

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Camera in measurement position: 250 mm behind first KTN surface (2w = 1.37 mm)

1 mm



TEC PWM duty cycle: Measured by detecting radiation close to TEC cable f = 14 kHzDuty cycle at room temperature: ~ 6.2%

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Experiment I: No HV

- UV LED switched on for 10 sec prior to measurements
- P_m: Average power incident on KTN
- 2w_f = 0.50 mm

1 mm



- No unexpected beam deformation (comparable to beam without KTN)
- > TEC duty decreases linearly with increasing laser power: Constant, linear absorption in KTN



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Experiment II: Constant HV

- UV LED switched on for 10 sec prior to Precharges
- Precharges: -200 V 10 sec and +300 V 10 sec
- DC Offset: -240 V
- $2w_f = 0.50 \text{ mm}$

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P _m =	2.0 W	7.6 W	18.8 W	40.7 W
TEC duty =	6.0%	5.8%	5.3%	4.6%
Defl. angle =	13.0 mrad	12.4 mrad	11.8 mrad	11.0 mrad

Less deflection with increasing laser power (KTN temperature constant at 26.0°C)

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Experiment III: AC HV 0.50 mm

- UV LED switched on for 10 sec prior to Precharges
- Precharges: -200 V 10 sec and +300 V 10 sec
- DC Offset: -240 V
- AC: 1 kHz, 360 V_{pp}
- $2w_{f} = 0.50 \text{ mm}$
- Again, reduced deflection angle for increasing laser power
- Varying energy distribution with increasing laser power

 $P_m =$





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2 mm

Experiment IV: AC HV 0.22 mm

- UV LED switched on for 10 sec prior to Precharges
- Precharges: -200 V 10 sec and +300 V 10 sec
- DC Offset: -240 V
- AC: 1 kHz, 360 V_{DD}
- $2w_{f} = 0.22 mm$
- Much stronger deflection angle reduction at increasing laser power due to smaller beam diameter
- Changing energy distribution with increasing laser power
- Increased impact of higher V_{pp} at max. laser power

 $P_m =$

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4.6% 4.2% 3.0% 2.7% 11.9 mrad ~1.5 mrad 22.7 mrad 600 V_{pp} In cooperation with NTT AT Corp. and Univ. Twente Peter Bechtold Institute of Photonic Technologies, Univ. Erlangen, Germany



2 mm



Exemplary demonstrations



Contrast ratio of rectangle waveform: 5.5:1

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TEC duty cycle over average power



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- TEC duty cycle linearly dependent on average power
- Will cross x-axis at approximately
 130 W ... 180 W
- Increased TEC current at room temperature will allow for higher laser powers
- Active cooling of the surroundings may be beneficial (i.e. lowering TEC duty cycle at 0 W laser power)

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Deflection per volt over average laser power



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- Deflection decreasing with increasing laser power
- Crystal is heated up locally, partly loosing ability to deflect the beam (i.e. lateral temperature gradient)
- Severe impact of decreased beam diameter and increased intensity
- May be compensated by higher deflection voltage (is not the case for lower intensity), compare page 6

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Deflection per volt over laser intensity



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Technologien

- Beam deflection angle
 reduction due to
 lateral temperature
 gradient is dependent
 on laser intensity
- Effect may be counteracted by increasing the voltage for higher intensities

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KTN crystal topography

Optical microscope



- There was no observable damage induced during any of the experiments
- The crystal is suitable for cw intensities of at least 2.6 10⁵ W/cm² (wavelength 1070 nm)

Confocal microscope



Topography before experiments



Topography after experiments



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Concluding max. applicable laser power

Damage threshold	:	The maximum intensity used in these experiments: $2w_f = 0.22 \text{ mm}; P_m = 48.8 \text{ W} \rightarrow 2.6 10^5 \text{ W/cm}^2$ The crystal was not damaged by this intensity (compare page 11) Increasing the beam diameter to 0.7 mm will lead to ~0.1 % absorbed laser power (taking the rectangular aperture into account). At the same intensity, this would allow for at least 490 W laser power.
Temperature stabilization	•	Increasing the TEC duty cycle at room temperature to approximately 20% would allow for ~ 530 W laser power, compare page 8
Lateral temperature	•	The deflection angle is halved at around 1.2 10 ⁵ W/cm ² and vanishes for 2.5 10 ⁵ W/cm ² , compare page 10. I.e. at a beam diameter of 0.7 mm this

- te gradient
- corresponds to 230 W and 480 W. Higher deflection voltages might counteract this effect and allow for increased laser power.
- With slight adaptions (increased beam diameter, increased PWM duty cycle), the KTN crystal would be usable up to at least 230 W ... 480 W of laser power.
- With further adaptions (increased aperture) the maximum laser power will even be higher.



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Further discussion

- 230 W ... 460 W of laser power are enough for efficient welding and selective laser melting.
- The varying beam profile deformation, varying energy distribution and decreasing deflection angle (amplitude) heavily suggest that a closed-loop control will be needed for deflecting high-power cw laser beam with KTN scanners in a controlled manner, compare results on pages 5 and 6.
- Exemplary results on page 7 show the application as semi-simultaneous beam shaping device and semi-simultaneous beam divider.



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